



1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Pas

Docket No.: TI-22398

Serial No.: 09/758,610

Art Unit: 1763

Filed: 01/11/01

Examiner: Moore, Karla A.

Title: System and Method for Integrating Oxide Removal and Processing Of a Semiconductor Wafer

AMENDMENT UNDER 37 CFR 1.111

February 26, 2004

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(A)

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service on 2-26-04 as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Karen Vertz 2-26-04  
Karen Vertz Date

In response to the Office Action, dated 11/26/2003, in the above-identified patent application, please make the following amendments. They are respectfully submitted as a full and complete response to that Action. Charge any required fees to the deposit account of Texas Instruments Incorporated, Account No. 20-0668.